



#6/A PB

Atty. Docket No. 8053-1008
PATENTS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

5/22/03

In re application of

NAITOU et al.

Confirmation No. 7712

Serial No. 09/981,390

GROUP 2878

Filed October 18, 2001

Examiner Phillip A. Johnston

SCANNING PROBE MICROSCOPE WITH
PROBE FORMED BY SINGLE CONDUCTIVE MATERIAL

AMENDMENT

Commissioner for Patents

Washington, D.C. 20231

Sir:

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MAY 14 2003
TECHNOLOGY CENTER 2800

Responsive to the Official Action of February 14, 2003,
please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 1, replace the paragraph, beginning on line 6, as
follows:

A1
--The present invention relates to a scanning probe
microscope such as a scanning capacitance microscope (SCaM).--

Page 1, replace the paragraph, beginning on line 19,
bridging pages 1 and 2, as follows:

A2
--In the above-described prior art scanning probe
microscope, however, since the coated metal of the cantilever is
so thin that the coated metal has a high impedance, i.e., a low
conductivity, the sensitivity of a sensor connected to the probe
is substantially decreased. Also, since the coated metal of the
cantilever has a larger surface to create a large stray
capacitance between the cantilever and the sample, a signal